

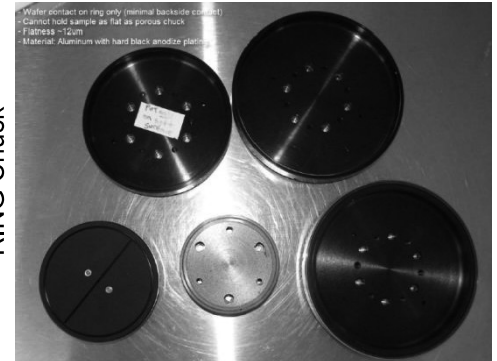
8720 System : Wafer Handler

– Scan Chuck

- Candela employs 3 different type of chucks, the comparison of which are given below:

Characteristics	RING	POROUS	PEEK
Material	Aluminum with hard black anodized plating	Alumina (proprietary composition / porosity)	Poly Ether Ether Ketone
Available Sizes	2", 3", 4", 5" & 6"	2", 3", 4", 5", 6" & 8"	4", 6" & 8"
Wafer Contact	On ring only	Uniform contact across wafer backside	Uniform contact across wafer backside
Vacuum Creation	On ring only	Across the complete porous material	Across multiple vacuum channels available
Typical Application	SiC, Epi SiC, GaN on SiC	Sapphire, PSS, GaN on Sapphire, GaN on PSS, GaN on Si, Si, Ge, GaSb, InSb	Si, GaN on Si or wafers with very rough back side

RING Chuck



POROUS Chuck



PEEK Chuck

